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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Serial No.: TO BE ASSIGNED

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Applicant: Toru YAMADA et al.

Art Unit: TO BE ASSIGNED

Filed: June 14, 2006

Examiner: TO BE ASSIGNED

Docket No: SUG-193-PCT

Customer No: 28892

For: Vapor Phase Growth Apparatus and Method of Fabricating Epitaxial Wafer

PRELIMINARY AMENDMENT

US Patent & Trademark Office

Customer Service Window, Mail Stop: **PATENT APPLICATIONS**

Randolph Building

401 Dulany Street

Alexandria, VA 22314

Sir:

After assigning a serial number to the above-captioned application and before calculating the fee, please undertake the following changes:

Amendments to the Specification begin on page 2 of this paper.

Amendments to the Claims are reflected in the listing of claims which begins on page 3 of this paper.

Remarks begin on page 7 of this paper.

An **Appendix** including the Abstract is attached following page 7 of this paper.